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# ***Emerging Digital Micromirror Device Based Systems and Applications X***

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# Contents

v	<i>Authors</i>
vii	<i>Conference Committee</i>

---

**SESSION 1 COMPUTATIONAL IMAGING FOR ADVANCED APPLICATIONS**

---

- 10546 02 **Where fewer pixels give you more image (Invited Paper)** [10546-1]
- 10546 04 **Single-pixel imaging using balanced detection and a digital micromirror device (Best Student Paper Award)** [10546-3]

---

**SESSION 2 ADVANCED MANUFACTURING USING DMD OR OTHER SLM: JOINT SESSION WITH CONFERENCES 10544 AND 10546**

---

- 10546 06 **Programmable CGH on photochromic material using DMD generated masks** [10546-5]

---

**SESSION 3 3D METROLOGY: JOINT SESSION WITH CONFERENCES 10544 AND 10546**

---

- 10546 0A **Superfast 3D shape measurement of a flapping flight process with motion based segmentation** [10546-8]
- 10546 0B **Universal phase unwrapping for phase measuring profilometry using geometry analysis** [10546-9]

---

**SESSION 4 BIOMEDICAL IMAGING WITH ADVANCED MICROSCOPY USING A DMD OR OTHER MEMS ARRAY**

---

- 10546 0D **Use of digital micromirror devices as dynamic pinhole arrays for adaptive confocal fluorescence microscopy** [10546-13]
- 10546 0E **DMD-based quantitative phase microscopy and optical diffraction tomography** [10546-14]

**SESSION 5 BIOMEDICAL IMAGING USING A DMD OR OTHER LIGHT STRUCTURING DEVICES FOR OPHTHALMOLOGICAL APPLICATIONS**

---

10546 0G **Confocal retinal imaging using a digital light projector with a near infrared VCSEL source (Best Paper Award)** [10546-16]

10546 0I **Structured polarized light microscopy (SPLM) for mapping collagen fiber orientation of ocular tissues** [10546-18]

**SESSION 6 NOVEL AND ADVANCED APPLICATIONS**

---

10546 0J **Low intensity LiDAR using compressed sensing and a photon number resolving detector (Invited Paper)** [10546-19]

10546 0K **Headlamp innovations: optical concepts for fully adaptive light distributions** [10546-20]

10546 0L **DMDs for multi-object near-infrared spectrographs in astronomy** [10546-21]